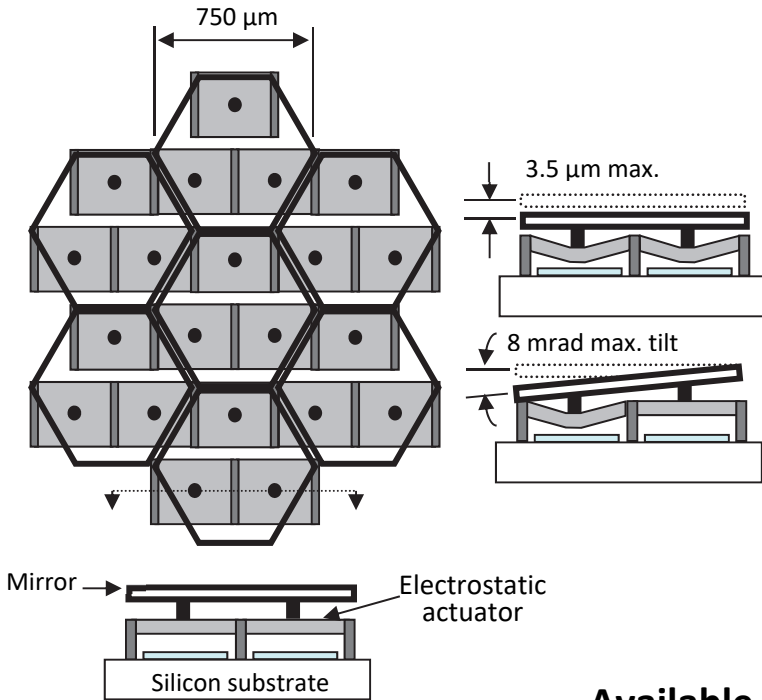
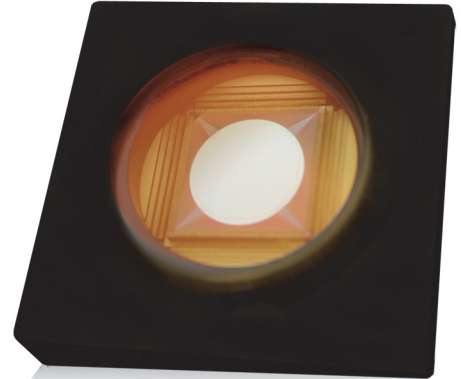


The Boston Micromachines Hex Class Deformable Mirrors offer an alternative to continuous and discrete segmented devices.

Well suited for an array of applications from *in vivo* microscopy to high-resolution astronomy, the Hex mirror architecture has the ability to tip, tilt and piston multiple segments for alternative wavefront control.



DM Architecture Specifications

- Segmented Surface
 - 3 actuators per segment
 - Coating: Gold or Protected Silver
 - Zero hysteresis
 - Fill Factor: >98%
 - Sub-nm average step size
 - Surface Finish: <40 nm RMS
 - Pitch: 375 μm
 - Segment Size: 750 μm
 - Maximum Tilt angle: ±8 mrad
 - Mechanical response: <40μs
 - Approx. interactuator coupling: 13%
- Full electro-mechanical calibration available**

Available Systems

	Hex-111	Hex-111-X	Hex-507	Hex-507-LL	Hex-507-S	Hex-1011	Hex-1011	Hex-1011-S
Actuator Count	111	111	507	507	507	1011	1011	1011
Segment Count	37	37	169	169	169	337	337	337
Stroke	3.5 μm	3.5 μm	3.5 μm	3.5 μm	1.0 μm	3.5 μm	3.5 μm	1.0 μm
Circular Aperture	3.8 mm	3.8 mm	8.3 mm	8.3 mm	8.3 mm	11.6 mm	11.6 mm	11.6 mm
Interface	USB	CameraLink via PCIe	SFP Fiber via PCIe			SFP Fiber via PCIe		
Resolution	14 bit	14 bit	14 bit	14 bit	12 bit	14 bit	14 bit	12 bit
Frame Rate (Latency)	2kHz (125μs)	100kHz (2μs)	45kHz (22μs)	60kHz (17μs)	60kHz	45kHz (22μs)	60kHz (17μs)	60kHz

For pricing and availability, please contact us at

